Application/Control No. Applicant(s)/Patent Under Reexamination 10/789,913 NAKAMURA, HIROKI Notice of References Cited Examiner Art Unit Page 1 of 1 Chen-Wen Jiang 3744 **U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	Α	US-2001/0049943 A1	12-2001	Nakamura et al.	62/176.6
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